

Journal of Alloys and Compounds 452 (2008) 116-121

Journal of ALLOYS AND COMPOUNDS

www.elsevier.com/locate/jallcom

Chemical vapour deposition of WSi₂ thin films: Equilibrium W–Si–H–Cl–Ar system

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Abstract

Tungsten disilicide (WSi₂) can be used in lieu of polycrystalline silicon in very large scale integrated (VLSI) circuit manufacturing; WSi₂(s) thin films have been deposited from a vapour-mix of WCl₄, SiH₂Cl₂ (or SiH₄), H₂, and an argon diluent. The present work describes an equilibrium model for the W–Si–H–Cl–Ar system: the feed-gas mixture is characterized by the atom-ratios (Ar/H), (H/Cl), and (W/Si); during the chemical vapour deposition (CVD), only the latter ratio is expected to change as one or more of condensed phases Si(s), WSi₂(s), W₅Si₃(s) and W(s) begin to form. In this work, the CVD-phase diagram was constructed by means of an *iterative method* that was coupled to the De Donder's extent of reaction formalism; the respective phase-domain boundaries Si(s) + WSi₂(s)/WSi₂(s)/WSi₂(s) + W₅Si₃(s) were computed for the temperature range of 800–1000 K at 1 atm (101.325 kPa); the SiH₂Cl₂-content of the feed-gas mixture, characterized by *F* = [Si⁰/(Si⁰ + W⁰)], was gradually decreased ensuring a complete sweep from the Si(s) + WSi₂(s) two-phase-domain to the phase-mixture WSi₂(s) + W₅Si₃(s) for specific (H/Cl) and (Ar/H) ratios. The results are of value in determining the CVD-phase diagrams for the growth of crystalline materials. © 2007 Elsevier B.V. All rights reserved.

Keywords: Tungsten silicides; Chemical vapour deposition model; Phase diagram

1. Introduction

The tungsten-silicon equilibrium phase diagram [1] shows the presence of two stoichiometric silicide compounds: WSi₂(s) and W₅Si₃(s); and their deposition from fluoride (W-Si-H-F-Ar) or chloride (W-Si-H-Cl-Ar) systems, with the inert argon serving as the carrier-gas, have been reported in the literature [1–3]. The chemical vapour deposition of WSi₂(s) from gas mixtures consisting of tungsten hexafluoride (WF₆), silane (SiH₄), and hydrogen (H₂) is regarded feasible only within a narrow range of feed-gas compositions; contamination due to undesired co-deposition of Si(s) or W₅Si₃(s) has been reported [1]. Thomas et al. [2] studied the deposition of WSi₂(s) films using a WCl₄ + SiH₄ + H₂ + Ar gas mixture at 873 K and a low pressure of 1 Torr (133 Pa); the siliconfraction *F*, defined as [Si/(Si + W)]⁰ of the feed-gas, was found to exercise a strong influence on the nature of the crystal-

0925-8388/\$ – see front matter © 2007 Elsevier B.V. All rights reserved. doi:10.1016/j.jallcom.2007.01.172 deposit; at F = 0.77, silicon deposited together with WSi₂(s); as *F* was decreased to 0.625, for W⁰/Si⁰ = 0.6 in feed-gas, the deposit became a WSi₂(s) + W₅Si₃(s) mixture [2]. Subsequent work of Thomas et al. [3] involved the use of a cold-wall reactor (at 873 K and 665 Pa total pressure) to grow tungsten silicide films from the W–Si–H–Cl–Ar system; the phase composition of the deposited films, determined by Xray diffraction and electron microscopy, corresponded to the WSi₂(s)-stoichiometry.

Vahlas et al. [1] employed the method of Gibbs free energy minimization and the entailed software packages to determine the equilibrium CVD-phase diagram for the WCl₄+SiH₂Cl₂+H₂+Ar system, at 1000 K and 1.0 atm (101.325 kPa) total pressure, with 90 mol% argon in the feed-gas. In the present work, an iterative equilibrium constant method [4] was used together with the De Donder's extent of reaction formalism [5] to determine WSi₂(s) domain boundaries: the feed-gas mixture was constituted from WCl₄, SiH₂Cl₂, H₂ and argon with the respective atom-ratios (Ar/H) and (H/Cl) held constant (ensuring conformity with the lever rule) while the silicon-mole-fraction (*F*) of the WCl₄ + SiH₂Cl₂

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vapour-mixture, or the $[Si/(W+Si)]^0$ atom-ratio of feed-gas, was gradually decreased at fixed WCl₄.

2. Equilibrium model of the W-Si-H-Cl-Ar system

The gas-phase in equilibrium with $WSi_2(s)$ and Si(s) or $W_5Si_3(s)$ at high temperatures contains 11 species, represented by digital notation as follows—WCl₄: 1, SiH₂Cl₂: 2, HCl: 3, H₂: 4, SiHCl₃: 5, SiCl₄: 6, SiCl₃: 7, SiCl₂: 8, WCl₅: 9, Ar: 10, SiH₄: 11.

The Gibbs stoichiometric rule gives $r = N - C^*$; *r* is the number of independent reactions, *N* the number of species and *C** is kinds of atoms present. Depending upon the species present, the independent set (*r*) is chosen from the following equilibria:

 $WSi_2(s) + 4HCl = WCl_4 + 2Si(s) + 2H_2, \epsilon_0$ (0)

$$WCl_4 + 2SiH_2Cl_2 + 2H_2 = WSi_2(s) + 8HCl, \quad \varepsilon_1$$
(1)

$$2HCl + SiH_2Cl_2 = SiCl_4 + 2H_2, \quad \varepsilon_2 \tag{2}$$

$$HCl + SiH_2Cl_2 = SiCl_3 + 1.5H_2, \quad \varepsilon_3$$
(3)

 $SiCl_2 + H_2 = SiH_2Cl_2, \quad \varepsilon_4 \tag{4}$

$$SiHCl_3 = SiCl_2 + HCl, \quad \varepsilon_5 \tag{5}$$

 $WCl_5 + 0.5H_2 = WCl_4 + HCl, \quad \varepsilon_6 \tag{6}$

$$SiH_4 + 2HCl = SiCl_2 + 3H_2, \quad \varepsilon_7 \tag{7}$$

$$WSi_2(s) + 2.8H_2 = 0.2W_5Si_3(s) + 1.4SiH_4, \quad \varepsilon_8$$
(8)

For the WSi₂(s) + Si(s) + gas system, N = 13 and r = 8; thus, Eqs. (0)–(7) represent the eight independent reactions. Using the extents of reactions ε_0 , ε_1 , ..., ε_7 and the feed-gas composition $(Q_1^0, Q_2^0, Q_4^0 \text{ and } Q_{Ar}^0, \text{ mol})$, the respective molar amounts of the 13 species are expressed by the following relations:

$$Q_1 = Q_1^0 + \varepsilon_0 - \varepsilon_1 + \varepsilon_6 : \quad \text{WCl}_4 \tag{9a}$$

$$Q_2 = Q_2^0 - 2\varepsilon_1 - \varepsilon_2 - \varepsilon_3 + \varepsilon_4 : \quad \text{SiH}_2\text{Cl}_2 \tag{9b}$$

$$Q_3 = -4\varepsilon_0 + 8\varepsilon_1 - 2\varepsilon_2 - \varepsilon_3 + \varepsilon_5 + \varepsilon_6 - 2\varepsilon_7 : \text{HCl} \quad (9c)$$

$$Q_5 = -\varepsilon_5: \quad \text{SiHCl}_3 \tag{9d}$$

$$Q_{4} = Q_{4}^{0} + 2\varepsilon_{0} - 2\varepsilon_{1} + 2\varepsilon_{2} + 1.5\varepsilon_{3} - \varepsilon_{4}$$

- 0.5\varepsilon_{6} + 3\varepsilon_{7} : H_{2} (9e)

$$Q_{10} = Q_{\rm Ar}^0 \tag{9f}$$

 $Q_6 = \varepsilon_2 : \quad \text{SiCl}_4 \tag{9g}$

$$Q_7 = \varepsilon_3$$
: SiCl₃ (9h)

$$Q_9 = -\varepsilon_6: \quad \text{WCl}_5 \tag{9i}$$

$$Q_{13s} = 2\varepsilon_0 : \quad \text{Si(s)} \tag{9j}$$

$$Q_8 = -\varepsilon_4 + \varepsilon_5 + \varepsilon_7 : \quad \text{SiCl}_2 \tag{9k}$$

$$Q_{11} = -\varepsilon_7: \quad \text{SiH}_4 \tag{91}$$

$$Q_{12s} = \varepsilon_1 - \varepsilon_0 : \quad WSi_2(s) \tag{9m}$$

3. Method of calculation: WSi₂(s)/Si(s) + WSi₂(s) phase-boundary

For a feed-gas composed of $4 \,\mu mol$ (or $4 \times 10^{-6} \,mol$) WCl₄, 36 µmol SiH₂Cl₂, 9766.2 µmol H₂ and 89956 µmol Ar, which together amount to a volumetric flow of 2.2362 NL/min, it is readily seen that $Cl^0 = 88 \,\mu mol$, $H^0 = 19604.5 \,\mu mol$, $Ar^0 = 89956 \mu mol$, $W^0 = 4 \mu mol$, and $Si^0 = 36 \mu mol$, with the result the atom-ratios assume the values of $(Ar/H)^0 = 4.5885$; $(H/Cl)^0 = 222.78$; F, the silicon-fraction $[Si/(W + Si)]^0 = 0.90$ for the feed-gas. In order to fully define the equilibrium-state of this three-phase system, for specified pressure (101.325 kPa) and temperature (1000 K), the equilibrium partial pressures of 11 gaseous species must be found. An iterative method that makes use of the non-linear equilibrium constant relations together with a successive converging approximations scheme [4] is employed in the present computation. Using the standard chemical potential data of Knacke et al. [6], the equilibrium constants K_0 , K_1, \ldots, K_7 for the respective reactions (0), (1), ..., (7) were calculated. The values are 9.343×10^{-14} , 1.4684×10^{10} , 180,540, 21.667, 15.64, 3.2969×10^{-5} , 374,460, and 4.1204×10^{6} , respectively at 1000 K [6]. The species WCl₄, H₂, and Ar are chosen as *majors*; and the first iteration is begun with the following guesses for the partial pressures of the three selected species:

$$P_1 = 1.0 \times 10^{-26} P$$
 for WCl₄, $P_4 = 0.098 P$ for H₂,
 $P_{Ar} = 0.90 P$, where $P = 1.0 \text{ atm} (101, 325 \text{ Pa})$

The partial pressures P_3 , P_2 , P_6 , P_7 , P_8 , P_5 , P_9 , and P_{11} of the remaining gas species were computed using the equilibrium constant data for the eight foregoing reactions:

$$P_{3} = \left[\frac{P_{1}(P_{4})^{2}}{K_{0}}\right]^{0.25}, P_{2} = \left[\frac{P_{3}^{8}}{K_{1}P_{1}P_{4}^{2}}\right]^{0.5},$$

$$P_{6} = K_{2}P_{2}\left(\frac{P_{3}}{P_{4}}\right)^{2}, P_{7} = \frac{K_{3}P_{2}P_{3}}{P_{4}^{1.5}},$$

$$P_{8} = \frac{P_{2}}{K_{4}P_{4}}, P_{5} = \left[\frac{P_{3}P_{8}}{K_{5}}\right],$$

$$P_{9} = \left[\frac{P_{1}P_{3}}{K_{6}P_{4}^{0.5}}\right], \text{ and } P_{11} = \left[\left(\frac{P_{4}^{3}P_{8}}{K_{7}P_{3}^{2}}\right)\right]$$

. . .

At this stage, the *three constraints* are imposed: first, the total pressure P_e is found:

$$P_{e} = P_{1} + P_{2} + P_{3} + P_{4} + P_{5} + P_{6} + P_{7}$$
$$+ P_{8} + P_{9} + P_{10} + P_{11} \neq P$$
(10)

The next two constraints are the atom-ratios: for the gasphase, the elemental molar amounts CL_t , SI_t , W_{tot} , H_t , and A_{tot} for chlorine, silicon, tungsten, hydrogen and argon, respectively, are proportional to pressure terms as the CVD flow-system is normally maintained under isothermal conditions (at 1000 K, in this instance):

$$CL_{t} = 5P_{9} + 4P_{1} + 4P_{6} + 3P_{5} + 3P_{7} + 2P_{2}$$

+ 2P_{8} + P_{3} (11a)

$$W_{\rm tot} = P_1 + P_9 \tag{11b}$$

$$SI_t = P_2 + P_5 + P_6 + P_7 + P_8 + P_{11}$$
(11c)

$$H_{\rm t} = 2P_2 + 2P_4 + P_3 + P_5 + 4P_{11} \tag{11d}$$

$$A_{\rm tot} = P_{\rm Ar} \tag{11e}$$

The gas-phase atom-ratios at the completion of the firstiteration are as follows:

$$(H/Cl) = \frac{H_t}{CL_t} \neq 222.78: \quad (H/Cl)^0 \text{ of feed-gas}$$
(12)

$$(Ar/H) = \frac{A_{tot}}{H_t} \neq 4.5885$$
: $(Ar/H)^0$ of feed-gas (13)

The constraints embodied in Eqs. (10), (12) and (13) are not satisfied; the approach to convergence can be quantitatively expressed by constraining ratios R_1 , R_3 and R_4 :

$$R_1 = \frac{P}{P_e}: \text{ pressure, } R_3 = \frac{222.78\text{CL}_t}{H_t},$$
$$R_4 = \frac{4.5885H_t}{A_{\text{tot}}}$$

At full convergence, all three approach unity within a tolerance-limit of 0.0001. The partial pressures of the *majors* are now modified to give successive increments (or declines) by means of the following convergence formulas:

$$(P_1)_{\text{new}} = (P_1)_{\text{old}} R_1^{0.08} \left(\frac{1.0}{R_3}\right)^{0.02}$$
: for WCl₄ (14a)

$$(P_4)_{\text{new}} = (P_4)_{\text{old}} R_1^{0.025} R_3^{0.03} \left(\frac{1.0}{R_4}\right)^{0.05}$$
: for H₂ (14b)

$$(P_{\rm Ar})_{\rm new} = (P_{\rm Ar})_{\rm old} R_1^{0.02} R_4^{0.01}$$
: for Ar (14c)

These new values for the *majors* are used together with K_0 , K_1, \ldots, K_7 to calculate the partial pressures of the eight other species; and the computation is continued until the convergence is reached at the end of 610 iterations (*wsi3.f* code). The equilibrium data in Pascals are shown in the second column of Table 1. The elemental quantities (in mol or μ mol) summed over the 11 species of the gas-phase are

$$Q_{Ar} = Q_{Ar}^{0}, \qquad Q_{Si} = Q_{2}^{0} - 2\varepsilon_{1}, \qquad Q_{W} = Q_{1}^{0} - \varepsilon_{1} + \varepsilon_{0},$$
$$Q_{Cl} = 4Q_{1}^{0} + 2Q_{2}^{0}, \qquad Q_{H} = 2Q_{1}^{0} + 2Q_{2}^{0}$$

Furthermore, defining SI_t, W_{tot} and CL_t as per Eqs. (11a)–(11c), and using P_i 's of Table 1:

SI_t = 11.90179,
$$W_{\text{tot}} = 6.539 \times 10^{-20}$$
, CL_t = 89.35906 Pa



Fig. 1. Phase-boundaries in the W–Si–Cl–H–Ar chemical vapour deposition (CVD) system at 101.325 kPa (1.0 atm) for (H/Cl) = 222.78 and (Ar/H) = 4.5885.

In view of $W_{\text{tot}} \approx 0$, the gas-phase tungsten $Q_W = 0 = Q_1^0 - \varepsilon_1 + \varepsilon_0$ which yields

$$\varepsilon_1 = Q_1^0 + \varepsilon_0 =$$
extent of reaction (1) at equilibrium (15a)

$$[SI_t/CL_t] = S_2 = 0.13319 = \frac{Q_{Si}}{Q_{Cl}} = \frac{Q_2^0 - 2\varepsilon_1}{4Q_1^0 + 2Q_2^0}$$
(15b)

In Eq. (15a), the limiting value of $\varepsilon_0 = 0$ corresponds to zeroamount of Si(s) as given in Eq. (9j); consequently, ε_1 in Eq. (15b) is replaced by Q_1^0 . Hence, the feed-gas that corresponds to the *boundary* between the phase-domains consists of $Q_1^0 = 4 \mu \text{mol}$ of WCl₄ and

$$Q_2^0 = Q_1^0 \left[\frac{2+4S_2}{1-2S_2} \right] = 13.81 \,\mu\text{mol SiH}_2\text{Cl}_2 \text{ and}$$

$$F = 0.7754$$
(16)

This result is marked '**a**, **b**' in Fig. 1; this lies on the frontier between the two-solid $Si(s) + WSi_2(s)$ domain and the single-solid $WSi_2(s)$ region of stability.

4. Equilibrium gas-phase partial pressures over WSi₂(s)

There occur the same 11 gas species in the equilibrium system containing only one solid, WSi₂(s); the set of independent reactions now consists of Eqs. (1)–(7) and the four constraints include the $[(Si-2W)/CI]^{(g)}$ stoichiometric ratio and the three listed earlier. The equilibrium-state is determined by the iterative equilibrium constant method [4] for a feed-gas with 4 µmol WCl₄, 13.81 µmol SiH₂Cl₂ and sufficient H₂ and Ar to ensure (H/Cl) = 222.78 and (Ar/H) = 4.5885, respectively. The results are shown in column 3 of Table 1 (*wsi2.f* code). At the Si(s) + WSi₂(s)/WSi₂(s) *boundary*, the equality of partial pressures is evident for each gaseous species partaking in the equilibrium. Thus one can use the $\varepsilon_0 \rightarrow 0$ limit together with Eqs. (15a), (15b) and (16) to obtain a rapid determination of the boundary between the single-solid and the two-solid domains at other temperatures. The equilibrium calculations (*wsi2.f* and

Table 1

Equilibrium boundaries $WSi_2(s)/Si(s) + WSi_2(s)$ and $WSi_2(s)/WSi_2(s) + W_5Si_3(s)$ and partial pressures in the W-Si-Cl-H-Ar system at 101.325 kPa (1 atm) and 1000 K

	Run no.							
	#1	#2	#3	#4	#5	#6	#7	#8
F (feed-gas)	0.9000	0.7754 b	0.7500	0.7310	0.7125	0.6912	0.5000 v	0.6717 d
Q_1^0 (µmol)	4.0	4.0	4.0	4.0	4.0	4.0	4.0	4.0
Q_2^{0} (µmol)	36.0	13.81	12.0	10.87	9.913	8.953	4.0	8.18283
$Q_4^{\bar{0}}$ (µmol)	9766.2	4844.9	4443.6	4193.0	3980.7	3767.8	2669.3	3597.0
$Q_{\rm Ar}^{\bar{0}}$ (µmol)	89956	44589	40889	38579	36622	34660	24533	33085
WCl ₄ (Pa)	$\approx 7 \times 10^{-20}$	$pprox 7 imes 10^{-20}$	$\approx 6 \times 10^{-19}$	$pprox 3 imes 10^{-18}$	$\approx 2 \times 10^{-17}$	$pprox 2 imes 10^{-16}$	$\approx 1 \times 10^{-14}$	$\approx 1 \times 10^{-14}$
SiH ₂ Cl ₂ (Pa)	0.7042	0.7042	0.4347	0.2893	0.1801	0.08343	0.01504	0.01504
HCl (Pa)	51.407	51.396	60.353	67.049	73.537	80.938	87.630	87.636
H ₂ (Pa)	9924.0	9922.7	9919.3	9916.6	9913.7	9910.4	9907.0	9907.7
SiHCl ₃ (Pa)	7.0735	7.0737	5.1284	3.7932	2.5911	1.3214	0.2580	0.2581
SiCl ₄ (Pa)	3.4115	3.4113	2.9052	2.3878	1.7895	1.0047	0.2125	0.2125
SiCl ₃ (Pa)	0.2525	0.2526	0.1832	0.1355	0.09255	0.04721	0.00922	0.00922
SiCl ₂ (Pa)	0.4597	0.4598	0.2839	0.1890	0.1177	0.05454	0.00984	0.00984
WCl ₅ (Pa)	$\approx 3 \times 10^{-28}$	$\approx 3 \times 10^{-28}$	$\approx 3 \times 10^{-27}$	$pprox 2 imes 10^{-26}$	$\approx 1 \times 10^{-25}$	$\approx 1 \times 10^{-24}$	$\approx 8 \times 10^{-23}$	$\approx 8 \times 10^{-23}$
Ar (Pa)	91338	91339	91336	91335	91333	91331	91330	91329
SiH ₄ (Pa)	4.1×10^{-4}	4.1×10^{-4}	1.8×10^{-4}	1.0×10^{-4}	5.1×10^{-5}	1.9×10^{-5}	3.0×10^{-6}	3.0×10^{-6}
(Cl) ⁰ (µmol)	88.0	43.62	40.0	37.74	35.826	33.906	24.0	32.3657
$(H)^0$ (µmol)	19604.5	9717.58	8911.12	8407.64	7981.25	7553.5	5346.7	7210.4
$(Ar)^0$ (µmol)	89956	44589	40889	38579	36622	34660	24533	33085
(H/Cl)	222.78	222.78	222.78	222.78	222.78	222.78	222.78	222.78
(Ar/H)	4.5885	4.5885	4.5885	4.5885	4.5885	4.5885	4.5885	4.5885
Fortran (program)	wsi3.f	wsi2.f	wsi2.f	wsi2.f	wsi2.f	wsi2.f	wsi4.f	wsi2.f

The letters **b**, **v** and **d** that appear in run nos. #2, #7 and #8 are shown in Fig. 1.

wsi3.f) presented in Fig. 1 show *boundary-values* of F = 0.8389 at 900 K and F = 0.8729 at 800 K, respectively. It is well to note that the amount of SiH₂Cl₂ in the feed-gas was increased with $Q_1^0 = 4 \mu \text{mol}$ of WCl₄; and the molar amounts of H₂ and argon were suitably chosen to ensure atom-ratios (H/Cl)⁰ and (Ar/H)⁰ remain constant at 222.78 and 4.5885, respectively.

At 1000 K and 101.325 kPa (1 atm) pressure, the equilibrium gas-phase above the WSi₂(s) was calculated for a number of feed-gas compositions: F = 0.750, 0.7310, 0.7125, 0.6912, with the SiH₂Cl₂-content gradually lowered. The resulting data on the partial pressures are shown in columns 4–7 of Table 1; it is seen that the variation of pressure for any given species is smooth within the single-solid WSi₂(s) domain.

5. Phase-boundaries: WSi₂(s)/W₅Si₃(s) + WSi₂(s)/ W₅Si₃(s)

The construction of the lower boundary – that separating the single-solid (WSi₂) from the two-solids (WSi₂ + W₅Si₃) region – in Fig. 1 is now addressed. It will be noted that the WSi₂(s) + W₅Si₃(s) + gas system at equilibrium consists of two solids and 11 gaseous species; the equilibria (1)–(8), given earlier, constitute the set of *eight independent reactions*. The four degrees of freedom possessed by this system require specification of *T*, *P*, (Ar/H), and (H/Cl) atom-ratios. For the feed-gas that is designated 'v' in Fig. 1 (4 µmol WCl₄, 4 µmol SiH₂Cl₂, 2669.3 µmol H₂, 24533 µmol Ar), one would expect the deposition of both W₅Si₃(s) and WSi₂(s) at 1000 K and 1.0 atm (101.325 kPa) pressure; the equilibrium gas-phase composition above the two-solids was computed (*wsi4.f* code) by means of the iterative equilibrium constant method [4]. The equilibrium partial pressure data (in Pa) for the 11 species are summarized in the column 8 of Table 1; the atom-ratios (H/Cl) and (Ar/H) are 222.78 and 4.5885. The molar amounts of the 13 species are expressed in terms of ε_1 to ε_8 and Q_i^0 's:

$$Q_1 = Q_1^0 - \varepsilon_1 + \varepsilon_6 : \quad \text{WCl}_4 \tag{17a}$$

$$Q_2 = Q_2^0 - 2\varepsilon_1 - \varepsilon_2 - \varepsilon_3 + \varepsilon_4 : \quad \text{SiH}_2\text{Cl}_2 \tag{17b}$$

$$Q_3 = 8\varepsilon_1 - 2\varepsilon_2 - \varepsilon_3 + \varepsilon_5 + \varepsilon_6 - 2\varepsilon_7 : \text{HCl}$$
(17c)

$$Q_5 = -\varepsilon_5: \quad \text{SiHCl}_3 \tag{17d}$$

$$Q_4 = Q_4^0 - 2\varepsilon_1 + 2\varepsilon_2 + 1.5\varepsilon_3 - \varepsilon_4 - 0.5\varepsilon_6 + 3\varepsilon_7 - 2.8\varepsilon_8 :$$

H₂ (17e)

$$Q_{10} = Q_{\rm Ar}^0 \tag{17f}$$

$$Q_6 = \varepsilon_2 : \quad \text{SiCl}_4 \tag{17g}$$

$$Q_7 = \varepsilon_3 : \quad \text{SiCl}_3 \tag{17h}$$

$$Q_8 = -\varepsilon_4 + \varepsilon_5 + \varepsilon_7 : \quad \text{SiCl}_2 \tag{17i}$$

$$Q_9 = -\varepsilon_6: \quad \text{WCl}_5 \tag{17j}$$

$$Q_{11} = 1.4\varepsilon_8 - \varepsilon_7 : \quad \text{SiH}_4 \tag{17k}$$

$$Q_{14s} = 0.2\varepsilon_8: \quad W_5 \operatorname{Si}_3(s) \tag{171}$$

$$Q_{12s} = \varepsilon_1 - \varepsilon_8 : \quad WSi_2(s) \tag{17m}$$

The molar amounts of elements Si, W and Cl, evaluated from the Q_i 's of the 11 gaseous species given by Eqs. (17a)–(17k), are as follows

$$Q_{\rm Si} = Q_2^0 - 2\varepsilon_1 + 1.4\varepsilon_8, \qquad Q_{\rm W} = Q_1^0 - \varepsilon_1,$$

 $Q_{\rm Cl} = 4Q_1^0 + 2Q_2^0$

Using the data on equilibrium pressures (Table 1, column 8) for feed-gas 'v' (Fig. 1), the values of the quantities SI_t , W_{tot} and CL_t are determined by means of Eqs. (11a)–(11c):

$$SI_t = 0.504615, \qquad W_{tot} = 1.025 \times 10^{-14},$$

 $CL_t=89.3314\,Pa$

Since W_{tot} for the gas-phase is negligibly small, $Q_{\text{W}} = 0 = Q_1^0 - \varepsilon_1$ and,

$$\varepsilon_1 =$$
 equilibrium extent of reaction $= Q_1^0$ (18a)

The frontier between $WSi_2(s)$ and $W_5Si_3(s) + WSi_2(s)$ domains is now found using the stoichiometric ratio S_2 introduced earlier by Eq. (15b):

$$S_2 = [SI_t/CL_t] = 0.0056488 = \frac{Q_{Si}}{Q_{Cl}} = \frac{Q_2^0 - 2Q_1^0 + 1.4\varepsilon_8}{4Q_1^0 + 2Q_2^0}$$
(18b)

In Eq. (18b), the limiting-value $\varepsilon_8 = 0$ corresponds to zeroamount of W₅Si₃(s) in the two-solids domain, as per Eq. (17l). Solving for *boundary feed-gas* Q_2^0 of SiH₂Cl₂:

$$Q_2^0 = Q_1^0 \left[\frac{2+4S_2}{1-2S_2} \right] = 8.18283 \,\mu\text{mol} \text{ and } F = 0.6717$$
 (19)

This result is shown in Fig. 1 (as 'c, d') at T = 1000 K and P = 101.325 kPa. Using a similar procedure, the boundary-limits (WSi₂/W₅Si₃ + WSi₂) at two other temperatures were determined: in Fig. 1, F = 0.7057 at 900 K and F = 0.7876 at 800 K represent the phase-boundary between solid-WSi₂ and the two-solid WSi₂ + W₅Si₃ domains.

The two-solid (WSi₂ + W₅Si₃) phase-region, with decreasing SiH₂Cl₂-content of the feed-gas, gives away to the single-solid domain W₅Si₃(s); the *boundary* between WSi₂(s) + W₅Si₃(s) and W₅Si₃(s) corresponds to zero-amount of WSi₂(s); therefore, by virtue of Eq. (17m), $\varepsilon_1 = \varepsilon_8$, which gives for the molar amount of silicon in gas-phase, $Q_{Si} = Q_2^0 - 2\varepsilon_1 + 1.4\varepsilon_8 = Q_2^0 - 0.6\varepsilon_1 = Q_2^0 - 0.6Q_1^0$; and Eq. (18b) now becomes

$$S_2 = [SI_t/CL_t] = 0.0056488 = \frac{Q_{Si}}{Q_{Cl}} = \frac{Q_2^0 - 0.6Q_1^0}{4Q_1^0 + 2Q_2^0}$$
(20a)

The feed-gas Q_2^0 of SiH₂Cl₂ at the WSi₂(s) + W₅Si₃(s)/W₅Si₃(s) *frontier* is given by

$$Q_2^0 = Q_1^0 \left[\frac{0.6 + 4S_2}{1 - 2S_2} \right] = 2.51884 \,\mu\text{mol} \text{ and } F = 0.3864$$
(20b)

Similar calculations at other temperatures provide F = 0.4620 (3.43493 µmol SiH₂Cl₂) at 900 K and F = 0.6310

(6.83968 μ mol SiH₂Cl₂) at 800 K, respectively. Thus, the *frontier* between the two-solid (WSi₂ + W₅Si₃) and the W₅Si₃(s) regions is found.

The upper-limit of the two-solids (WSi₂ + W₅Si₃) domain in Fig. 1 is further investigated at 1000 K and 101.325 kPa (1 atm) pressure for atom-ratios (H/Cl) = 222.78 and (Ar/H) = 4.5885; the single-solid (WSi₂) region ends at limit **'c**, **d'** (Fig. 1).

The equilibrium gas-phase partial pressures over WSi₂(s) were calculated (*wsi2.f* code) for the *boundary* feed-gas consisting of 4 µmol WCl₄, 8.18283 µmol SiH₂Cl₂, 3597 µmol H₂ and 33085 µmol Ar and the data are listed in column 9 of Table 1. It is well to note that there is near perfect agreement among partial pressures (columns 8 and 9) for each of the reacting gaseous species. This confirms that F = 0.6717 indeed denotes the *frontier* between WSi₂(s) and WSi₂(s) + W₅Si₃(s) phase-fields at 1000 K.

6. Discussion

The application of the lever rule is illustrated by the $WSi_2(s) + W_5Si_3(s)$ region, which at 1000 K is bounded by 'd' and 'z', as shown in Fig. 1; and the length 'dz' is measured in µmol units of the SiH₂Cl₂-content of the feed-gas, with $Q_1^0 = 4 \mu \text{mol WCl}_4$, and atom-ratios (H/Cl) = 222.78 and (Ar/H) = 4.5885. Referring to feed-gas (point 'v' in Fig. 1) with F = 0.50, listed in column 8 of Table 1, it was shown that the two-solid domain stretched from 8.18283 to 2.51884 µmol with the selected point 'v' at 4 µmol of the SiH₂Cl₂(g). This gives length 'dz' = 8.18283 - 2.51884 = 5.66399 µmol; and the amounts of WSi₂(s) and WSi_{0.6}(s) are proportional to lengths 'vz' and 'dv', respectively:

$$Q_{12s} = Q_1^0 \left[\frac{4.0 - 2.51884}{5.66399} \right] = 1.04602 \,\mu\text{mol of WSi}_2(s)$$
$$Q_{14s} = 0.2 Q_1^0 \left[\frac{8.18283 - 4.0}{5.66399} \right] = 0.5908 \,\mu\text{mol of W}_5 \text{Si}_3(s)$$

An independent verification of these results was obtained by determining the extents of reactions ε_1 to ε_8 from the data of Table 1 (column 8) as described elsewhere [4]:

$$\varepsilon_1 = 4 \,\mu\text{mol}, \qquad \varepsilon_3 = 2.477 \times 10^{-3} \,\mu\text{mol}, \qquad \varepsilon_2 = 23\varepsilon_3,$$

 $\varepsilon_7 = 4.1356 \,\mu\text{mol}, \qquad \varepsilon_8 = 2.954 \,\mu\text{mol}$

These upon substitution into Eqs. (17l) and (17m) yield values of $1.046 \,\mu\text{mol}$ for $WSi_2(s)$ and $0.5908 \,\mu\text{mol}$ for $W_5Si_3(s)$, respectively. Thus, the present work is seen to be in accord with the lever rule.

7. Conclusions

Using the iterative equilibrium constant method in combination with extent of reaction framework, the phase-boundaries between the single-solid and the two-solid regions were successfully established for W–Si–Cl–H–Ar chemical vapour deposition system. The application of lever rule was demonstrated for the two-solid $W_5Si_3(s) + WSi_2(s)$ domain.

Acknowledgements

The author acknowledges the valuable support of the staff of the University of Washington Academic Computer Center, Mary Gates Hall, Seattle. Thanks are also due to my son, Y. Vijay Rao.

References

 C. Vahlas, C. Bernard, R. Madar, in: K. Hack (Ed.), The SGTE Casebook. Thermodynamics at Work, Institute of Materials, London, UK, 1996, pp. 108–117.

- [2] N. Thomas, P. Suryanarayana, E. Blanquet, C. Vahlas, R. Madar, C. Bernard, J. Electrochem. Soc. 140 (1993) 475.
- [3] N. Thomas, A.M. Dutron, C. Vahlas, C. Bernard, R. Madar, J. Electrochem. Soc. 142 (1995) 1608.
- [4] Y.K. Rao, Stoichiometry and Thermodynamics of Metallurgical processes, Cambridge University Press, Cambridge, 1985 (Chapter 11).
- [5] I. Prigogine, Introduction to Thermodynamics of Irreversible Processes, 2nd ed., John Wiley & Sons, New York, 1961, Chapter I.
- [6] O. Knacke, O. Kubaschewski, K. Hesselmann (Eds.), Thermochemical Properties of Inorganic Substances, 2nd ed., Springer-Verlag, Berlin, Germany, 1991.